

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): G. MIYA, et al  
Serial No.: (not yet assigned)  
Filed: February 18, 2004  
For: PLASMA PROCESSING APPARATUS AND PLASMA  
PROCESSING METHOD

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

February 18, 2004

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, as listed below and as set forth on the following pages:

Amendment of the Specification and Abstract;  
Amendment of the Claims; and  
Remarks are included following the amendments.